

COPAG UV SIG-TIG Tech Development

**AAS 237 Splinter Session
January 14, 2021**

Some preliminary thoughts by Jason Tumlinson and Stephan McCandliss

Visit the Slack channel:

**#splinter_nasa_uv_vis_sig-and_tig
for discussion and any logistical issues.**

Context

1) The next UV / optical flagship (let's call it "LUVEx") will be built on technological "tall poles" that must be scaled for a number of mission-critical technologies.

These include, for example, mirror phasing control, high contrast coronagraphy, UV coatings, gratings, and MOS aperture masks, and large format detector arrays (and for HabEx, starshades).

2) Note that NASA practice holds that a mission should be at TRL6 by PDR. LUVOIR aims to be there at the start of Phase A. All the STDTs wrote their schedules for a 2025 New Start.

3) All the flagship STDTs laid out detailed technology development requirements, plans, and schedules for the first phases of the missions. Acting on these plans will be important for all of them, no matter which one gets ranked first.

4) And there is the complex matter of how to reach "system level" TRLs as opposed to "component level" TRLs.

5) While we await the decadal, and even after, we can still ask whether the technology develop currently underway add up to collective effort that is on track to advance TRLs to the stated goals.

What might this look like?

Table 11-1. Technology components in the high-contrast coronagraph instrument technology system.

Section	Technology Component	Implementation Options	State of the Art	Capability Needed	FY19 TRL	In LUVVOIR Baseline?
12.2.1.3	Coronagraph Architecture	Apodized Pupil Lyot Coronagraph (APLC)	6.3x10 ⁻⁶ over 6% bandpass in air. Validated models with WFIRST CGI SPC demonstrations	1x10 ⁻¹⁰ raw contrast >10% bandpass <4 λ/D inner working angle 64 λ/D outer working angle Robust to stellar diameter and jitter	4	✓
		Vortex Coronagraph (VC)	8.5x10 ⁻⁹ contrast over 10% band with unobscured pupil. SCDA modeling for unobscured, segmented pupil		3	✓
		Phase-Induced Amplitude Apodization (PIAA)	SCDA modeling results for unobscured, segmented pupil		3	
		Hybrid-Lyot Coronagraph (HLC)	3.6x10 ⁻¹⁰ contrast over 10% band in DST. SCDA modeling for unobscured segmented pupil		3	
		Nulling Coronagraph (NC)	5x10 ⁻⁹ narrowband at 2.5 λ/D		3	
12.2.1.4	Deformable Mirrors	Micro-Electro-Mechanical Systems (MEMS)	Available up to 64 x 64 actuators; 8.5x10 ⁻⁹ contrast demonstrated with 32 x 32 actuators	128 x 128 actuators Stable actuators (low creep)	4	✓
		Lead-Magnesium-Niobate (PMN) Macro-scale	<1x10 ⁻⁸ contrast demonstrated with 48 x 48 actuator Xinetics DMs (WFIRST CGI Testbed)	Diffraction-limited surface quality (< 3 nm surface roughness)	5	
12.2.1.7	Wavefront Sensing	Out-of-band Wavefront Sensing	Model predicting <10 pm residual error with nonlinear ZWFS, Mv = 5 source	Wavefront stability ~10 pm RMS	3	✓
		Low-order Wavefront Sensing	<0.36 mas RMS line-of-sight residual error; <30 pm RMS focus, Mv = 5 source (WFIRST CGI Testbed)	~1 Hz bandwidth with Mv < 9 source	6	✓
		Artificial Guide Star	Concept study for guide star spacecraft and wavefront sensing control loop completed.	Able to capture wavefront spatial frequencies on the order of segment-to-segment drift and DM actuators	3	
12.2.1.10	UV/VIS Low-noise Detector	Electron-Multiplying CCD	1k x 1k WFIRST Detector: 7x10 ⁻⁵ e-/pix/s dark current 0 e- read noise 2.3x10 ⁻³ CIC	3x10 ⁻⁵ e-/pix/s dark current 0 e- read noise	4	✓
		Hole-Multiplying CCD	Prototype devices fabricated with gains > 10x (>20x in at least one device)	1.3x10 ⁻³ e-/pix CIC >80% QE at all detection wavelengths 4k x 4k array size	3	
12.2.1.12	NIR Low-noise Detector	HgCdTe Photodiode Array	H4RG-10 currently meets needed capability @ 170 K	< 1x10 ⁻³ e-/pix/s dark current < 3e- read noise 4k x 4k array size	5	✓
		HgCdTe Avalanche Photodiode	1.5x10 ⁻³ e-/pix/s dark current < 1 e- read noise 320 x 256 array size Requires < 100 K temperatures		4	

Coronagraph

Table 11-2. Technology components in the ultra-stable segmented telescope technology system.

Section	Technology Component	Implementation Options	State of the Art	Capability Needed	FY19 TRL	In LUVVOIR Baseline?
12.2.2.4	Mirror Substrate	Closed-back ULE (rigid body actuated)	7.5 nm RMS surface figure area with no actuated figure correction	~5 nm RMS surface figure error > 400 Hz first free mode 19 kg/m ² areal density	5	✓
		Closed-back ULE (surface figure actuated)	< 200 Hz first free mode ~10 kg/m ² areal density		4	
		Open-back Zerodur (rigid body actuated)	Meets wavefront error requirement, but first mode and areal density are challenges		4	
12.2.2.6	Actuators	Combined piezo/mechanical	JWST mechanical actuators; Off-the-shelf PZT actuator with 5 pm resolution	> 10 mm stroke < 10 pm resolution < 1 pm / 10 min creep Long lifetime	3	✓
		All-piezo	20 mm travel with 5 nm coarse resolution and 5 pm fine resolution	3		
12.2.2.8	Edge Sensors	Capacitive	5 pm in gap dimension, 60 Hz readout	< 4 pm sensitivity at 50–100 Hz rate (control bandwidth of 5–10 Hz)	3	✓
		Inductive	1 nm / sqrt(Hz) for 1–100 Hz in shear; 100 nm / sqrt(Hz) for 1–10 Hz in gap		3	
		Optical	20 pm / sqrt(Hz) up to 100 Hz		3	
		High-speed Speckle Interferometry	< 5 pm RMS at kHz rates; requires center-of-curvature location and high-speed computing		3	
12.2.2.9	Laser Metrology	Laser truss with phasemeter electronics	Planar lightwave circuit; 0.1 nm gauge error; LISA-Pathfinder heritage laser	< 100 pm sensitivity at 10 Hz rate (control bandwidth of 1 Hz)	4	✓
12.2.2.11	Vibration Isolation	Non-contact Isolation System	> 40 dB transmissibility isolation > 1 Hz; Requires electronics development and performance validation	> 40 dB transmissibility isolation > 1 Hz	4	✓

Ultrastable Optics

These tables express the essence of LUVVOIR's tech development needs.

UV Instruments

Table 11-3. Technology components in the ultraviolet instrumentation technology system.

Section	Technology Component	Implementation Options	State of the Art	Capability Needed	FY19 TRL	In LUVVOIR Baseline?
12.2.3.4	Far-UV Broadband Coating	Al + eLiF + MgF ₂	Meets performance requirements, but requires demonstration on meter-class optics; requires validation of uniformity, repeatability, environmental stability	>50% reflectivity (100–115nm)	3	✓
		Al + eLiF + AlF ₃		>80% reflectivity (115–200nm)		
		Al + eLiF		>88% reflectivity (200–850nm) >96% reflectivity (> 850nm)		
12.2.3.6	Microshutter Arrays	Next-gen Electrostatic Microshutter Arrays	840 x 420 prototype demonstrated, but requires development to survive launch environment	840 x 420 array format, two-side buttable	3	✓
		CsI	Meets requirements for 100–150 nm	200 mm x 200 mm tile size >30% QE between 100–200 nm	6	✓
12.2.3.7	Large-format Microchannel Plates	GaN	Meet requirements for 150–200 nm range; requires development for large tile size and integration with cross-strip readout. GaN has better solar blind performance.		4	✓
		Bi-alkali	Demonstrated 50% improved quantum efficiency with CsI photocathode		4	
12.2.3.8	Large-format High-resolution Focal Plane Arrays	8k x 8k CMOS	4k x 4k devices exist, require development for 8k x 8k and readout optimization		8k x 8k format, <7 micron pixels, three-side buttable	4
		4k x 4k CCD	8k x 8k devices exist with 18 micron pixels; lacks programmable high-speed region-of-interest readout for guiding capability	~1 e- read noise ~1x10 ⁻⁴ e-/pix/s dark current at 170 K	5	

LUVOIR UV/Optical Technologies

Based on Table 11-3 of LUVOIR Report

7	System prototype demonstration in an operational environment.											
LUVOIR Preliminary Design Review												
6	System / sub-system model or prototype demonstration in an operational environment.											
5	Component and/or breadboard validation in relevant environment.											
4	Component and/or breadboard validation in lab environment											
3	Analytical and experimental critical function and/or characteristic proof of concept											
		> 50% over 100-115 nm, > 80% over 115-200 nm > 88% over 200 - 850 nm, > 96% over > 850 nm, < 1% reflectance non-uniformity over primary mirror in coronagraph bandpass (200-2000 nm)			840x420 format, two-side buttable, high contrast		200 mm x 200 mm tile size > 30% QE between 100-200 nm				8K x 9K format, < 7 μm pixels, three-side buttable, ~1 e- read noise, 10 ⁻⁴ e-/pix/s dark at 170K	
		Al+eLiF+MgF ₂ Baseline	Al+eLiF+AlF ₃	Al+eLiF	Microshutters Baseline	Micromirrors	CsI Baseline	GaN Baseline	Bi-alkali	Funnel micro	8K x 8K CMOS Baseline	4K x 4K CCDs
		Far-UV Broadband Coatings <small>LUVOIR pg. 11-25</small>			Configurable Shutters <small>LUVOIR pg. 11-26</small>		UV Microchannel Plate <small>LUVOIR pg. 11-26</small>				Visible Detectors <small>LUVOIR pg. 11-27</small>	

LUVOIR UV/Optical Technologies

Based on Table 11-3 of LUVOIR Report

Black font = current status as of 2018, from Table 11-3 of LUVOIR Final Report

7	System prototype demonstration in an operational environment.												
LUVOIR Preliminary Design Review													
6	System / sub-system model or prototype demonstration in an operational environment.							meets requirements for 100-150 nm					
5	Component and/or breadboard validation in relevant environment.			Meets performance requirements, but is environmentally unstable									8K x 8K devices exist with 18 micron pixels, lacks high speed subarray readout for guiding
4	Component and/or breadboard validation in lab environment					>5000:1 contrast achieved on re-windowed XGA format (1024x768) Ninkov SAT ; Quad		meets requirements for 100-150 nm; requires devel for large tile size and integration with cross-strip readout. GaN has better Solar-blind performance		Demonstrated 50% improved QE with CsI photocathode	4K x 4K devices exist, require development for 8K x 8K and readout optimization		
3	Analytical and experimental critical function and/or characteristic proof of concept	Meets performance requirements, but requires demonstration on meter-class optics, validation of uniformity, repeatability, and env. stability PVD; Quijada SAT; Quad			840x420 prototype demonstrated, but requires devel. to survive launch Greenhouse SAT ; Quad								
		> 50% over 100-115 nm, > 80% over 115-200 nm > 88% over 200 - 850 nm, > 96% over > 850 nm, < 1% reflectance non-uniformity over primary mirror in coronagraph bandpass (200-2000 nm)			840x420 format, two-side buttable, high contrast		200 mm x 200 mm tile size > 30% QE between 100-200 nm				8K x 9K format, < 7 μm pixels, three-side buttable, ~1 e- read noise, 10 ⁻⁴ e-/pix/s dark at 170K		
		Al+eLiF+MgF ₂ Baseline	Al+eLiF+AlF ₃	Al+eLiF	Microshutters Baseline	Micromirrors	CsI Baseline	GaN Baseline	Bi-alkali	Funnel micro	8K x 8K CMOS Baseline	4K x 4K CCDs	
Far-UV Broadband Coatings LUVOIR pg. 11-25					Configurable Shutters LUVOIR pg. 11-26		UV Microchannel Plate LUVOIR pg. 11-26				Visible Detectors LUVOIR pg. 11-27		

Development of Digital Micro-mirror Devices for Far-UV Applications

PI: Zoran Ninkov / Rochester Institute of Technology



Objectives and Key Challenges:

- There is a need for a technology to allow for selection of targets in a field of view that can be input to an imaging spectrometer for use in remote sensing and astronomy
- We are looking to modify and develop Digital Micro-mirror Devices (DMDs) for this application

Significance of Work:

- This work looks to improve the deep-UV performance of COTS DMDs by recoating the DMD mirrors themselves using the coating facility at GSFC and operating them with a custom window or operating in an open mode

Approach:

- Use available 0.7 XGA DMDs that will be recoated with a Al/AlF₃ at GSFC coating facility; test and evaluate such devices both with a window and in an open configuration

Key Collaborators:

- Manuel Quijada and Javier del Hoyo (NASA/GSFC)
- Massimo Robberto (STScI)
- Alan Raisanen (RTI)
- Stephen Smees (JHU)
- Dmitry Vorobiev (U Colorado, Boulder)

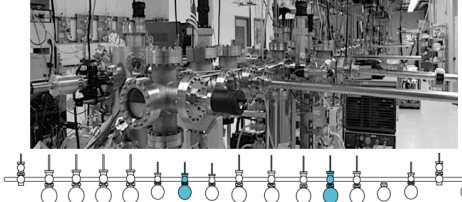
Current Funded Period of Performance:

Jan 2018 – Dec 2019

TRL_{in} = 5 TRL_{Current} = 5 TRL_{Target} = 5

Use of Plasma Enhanced ALD to Construct Efficient Interference Filters for the FUV

PI: Paul Scowen / ASU



Objectives and Key Challenges:

- Use a range of oxide and fluoride materials to build stable optical layers using Plasma-Enhanced Atomic Layer Deposition (PEALD) to reduce adsorption, scattering, and impurities
- Layers will be suitable for protective overcoats with high UV reflectivity and unprecedented uniformity (compared to thermal ALD)
- Development of single-chamber system to deposit metal oxide and dielectric layers without breaking vacuum

Significance of Work:

- To use the improved ALD capability to leverage innovative ultraviolet/optical filter construction

Approach:

- Development of existing PEALD system to a single-chamber model
- Atomic layer processing to remove surface oxides from Al
- Demonstration of fluoride deposition on top of Al films
- Demonstration of VUV reflectivity, uniformity, and stability

Key Collaborators:

- Paul Scowen, Robert Nemanich, Brianna Eller, Daniel Messina, Zhiyu Huang, and Hongbin Yu (ASU)
- Tom Mooney (Materion)
- Matt Beasley (Planetary Resources Inc.)

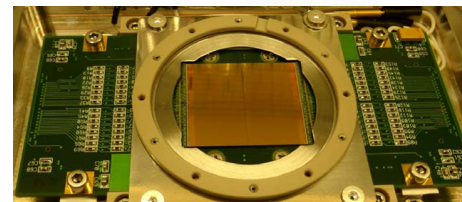
Current Funded Period of Performance:

Dec 2015 through Nov 2019

TRL_{in} = 3 TRL_{Current} = 3 TRL_{Target} = 4

Large format, high dynamic range UV Detector using MCPs and Timepix4 Readouts

PI: John Vallega / U.C. Berkeley



Description and Objectives:

Large format (200x200mm) MCP detectors have been baselined as the detector of choice for the far-UV instruments on the proposed LUVOR and HabEx missions. To scale to that size while maintaining spatial resolution and dynamic range requires a pixelated anode readout that can be mosaiced over this area. The new photon counting ASIC, called Timepix4 (Tpx4), has all these attributes: large format (28x25mm), buttable on 4 sides, low input noise (75e- rms), sparsified event readout, and events rates exceeding 100 MHz.

Key Challenge/Innovation:

- Demonstrating Tpx4 readout of MCPs with excellent spatial resolution, at very high event rates in a low-power mode
- Tpx4 mosaics with minimum gaps between ASICs (<50µm)
- New 100x100 MCP detector with Tpx4 readout to be environmentally tested (vibration, thermal, radiation)

Approach:

- Tpx4 ASICs will first be processed at the wafer level to create Through Silicon Vias (TSVs) and a signal redistribution layer on the backside to enable a ball-grid array pattern. A High Temperature Co-fired Ceramic (HTCC) circuit layout board will be designed to hold a 3x3 array of accurately aligned Tpx4 dies. Signals and Power/Gnd will be distributed on the back side of the HTCC including two 10Gbps transceivers per chip (18 total). This 84x74mm active anode will be placed in a 100x100 mm MCP detector to measure performance in flight like environments.

Key Collaborators:

- Timepix4/Medipix4 collaboration (14 international institutes) <http://medipix.web.cern.ch/collaboration/medipix4-collaboration>

Development Period:

- March 1, 2019 - Feb 28, 2022

Accomplishments and Next Milestones:

- Timepix4 wafer processed with TSVs and BGA redistribution layer - Jan 2021
- HTCC ceramic carrier fabricated. - Oct 2020
- Readout of single Tpx4 x-ray sensor using Kintex dev. board. - Oct 2020
- Mounting of Tpx4 dies onto HTCC carrier. - Apr. 2021
- Tpx4 anode with MCP detector assembly operating in vacuum - Oct 2021
- Fully functional MCP - Tpx4 detector with FPGA readout - Jan 2022
- Environmental tests of MCP-Tpx4 detector. - July 2022

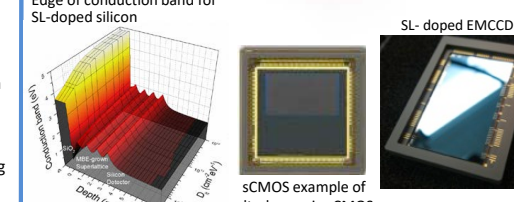
Applications:

- High performance UV (1-300nm) detector for astrophysics (LUVOR, HabEx, CETUS), planetary, solar, heliospheric, or astronomy missions
- Particle or time of flight detector for space physics missions
- Neutron radiography/tomography for material science

• TRL_{in} = 4 TRL_{Current} = 4 TRL_{Target} = 5

Advanced FUV/UV/Visible Photon-Counting and Ultralow-Noise Detectors

PI: Shouleh Nikzad / JPL, California Institute of Technology



Objectives and Key Challenges:

- Develop and advance TRL of solar-blind (SB), high-efficiency, photon-counting, and ultralow-noise solid-state detectors, especially in FUV ($\lambda < 200$ nm)
- Key challenges: SB silicon, large-format arrays, reliable and stable high response in FUV

Significance of Work:

- Key innovations are high and stable UV response through atomic-level control of surface and interfaces, the breakthrough in rendering Si detectors with optimized in-band response and out-of-band rejection, versatility with CMOS and CCD, and uniform large format

Approach:

- Fabricate and process UV detectors by superlattice (SL) doping Electron Multiplying CCDs (EMCCDs) and ultralow-noise CMOS wafers
- Develop multi-stack, integrated, SB filters using atomic-layer deposition (ALD)
- Combine integrated SB filters and SL with CMOS and EMCCDs
- Characterize and validate

Key Collaborators:

- Chris Martin (Caltech)
- David Schimminovich (Columbia University)
- Michael Hoenk (JPL)
- Teledyne-e2v, SRI, AMS-CMOSIS, Alacron

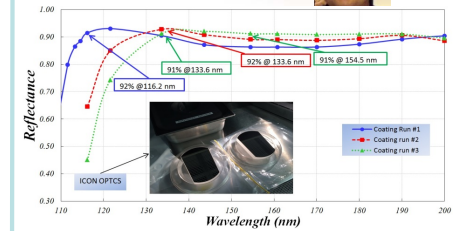
Current Funded Period of Performance:

Jan 2016 – Dec 2019

• TRL_{in} = 3 TRL_{Current} = 3 TRL_{Target} = 5

Enhanced MgF₂ and LiF Over-coated Al Mirrors for FUV Space Astronomy

PI: Manuel A. Quijada/Code 551



Description and Objectives:

- Development of high reflectivity coatings to increase system throughput, particularly in the far-UV (FUV) spectral range
- Study other dielectric fluoride coatings and other deposition technologies such as Ion Beam Sputtering (IBS) that is expected to produce the nearest to ideal morphology optical thin film coatings and thus low scatter

Key Challenge/Innovation:

- Achieving high reflectivity (> 90-95%) in the 90 to 250 nm range
- Scaling up coatings to large diameter (1+meter) mirror substrates

Approach:

- Retrofit a 2 meter coating chamber with heaters/thermal shroud to perform Physical Vapor Depositions at high temperatures (200-300 C) to further improve performance of Al mirrors protected with either MgF₂ or LiF overcoats.
- Optimize deposition process of lanthanide trifluorides as high-index materials that when paired with either MgF₂ or LiF will enhance reflectance of Al mirrors at Lyman-alpha.
- Establish the IBS coating process to optimize deposition of MgF₂ and LiF with extremely low absorptions at FUV wavelengths.

Key Collaborators:

- Javier del Hoyo, Steve Rice and Felix Threat (551)
- Jeff Kruk and Charles Bowers (665)

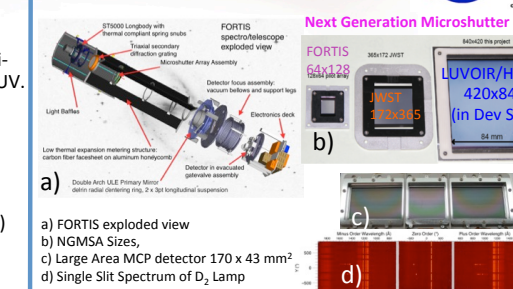
Development Period:

Oct. 1, 2011 – Sept. 30, 2014

• TRL_{in} = 3 TRL_{Out} = 4

Next Generation FORTIS

PI: Stephan McCandless/JHU



Description and Objectives:

- Demonstrate the scientific utility and feasibility of multi-object spectroscopy over wide angular fields in the far-UV. First Science Investigation: Spectroscopy of Hot Star Clusters in galaxy M33

Key Challenge/Innovation:

- Pulsed Actuated Next Gen Microshutter Arrays (NGMSA) and Longlife, High QE, Large Area Borosilicate MCP's
- Autonomous Target Acquisitions

Approach:

- Collaborate with GSFC on NGMSA requirements and fabrication
- Sensor Sciences retrofit detector with new borosilicate MCP's with CsI photocathode
- Develop Wide-Field Lyα Geocoronal Simulator (WFLaGS)
- Design light traps suppress Lyα
- Involve graduate and undergraduates all phases of mission

Key Collaborators:

- Brian Welch, Anna Carter, Paul Feldman, William Blair, Luciana Bianchi - JHU
- Matt Greenhouse, S. Harvey Moseley, Alexander Kutnyev, Mary Lu - GSFC
- Gerhardt Meurer - U. Western Australia

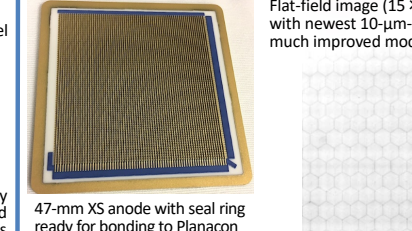
Development Period:

1 January 2017 to 31 December 2021

• TRL_{in} = 3 TRL_{Current} = 4 TRL_{Target} = 7

High-Performance Sealed-Tube Cross-Strip Photon-Counting Sensors for UV-Vis Astrophysics Instruments

PI: Oswald Siegmund / UC Berkeley



Objectives and Key Challenges:

- Exploit developments in atomic-layer-deposited (ALD) microchannel plates (MCPs), photocathodes, and cross strip (CS) readout techniques to implement a new generation of enhanced-performance sealed-tube photon-counting sensors that span the 115-nm to 400-nm regime; subcomponent areas have achieved considerable technical development, but putting them into a robust, integrated package, advancing the TRL from 4 to 6 for the next UV/Vis astrophysics instruments has not yet been attempted

Significance of Work:

- Format, performance, and capabilities of the scheme is directly relevant to the requirements specified for CETUS, LUVOR and HABEX, as well as upcoming SMEX, CubeSat and sub-orbital projects

Approach:

- Adopt current Photonis Planacoat 50-mm sealed tube and implement the new technologies within this envelope
- Implement UV MgF₂ entrance window and UV-optimized bilkaii semitransparent photocathode with narrow (~200-µm) proximity gap
- Replace standard MCPs with two ALD MCPs, depositing an opaque UV photocathode onto MCP input surface
- Replace pad-array anode with XS anode readout

Key Collaborators:

- Dr. T. Cremer (Incom Inc.)
- Dr. J. DeFazio (Photonis USA)

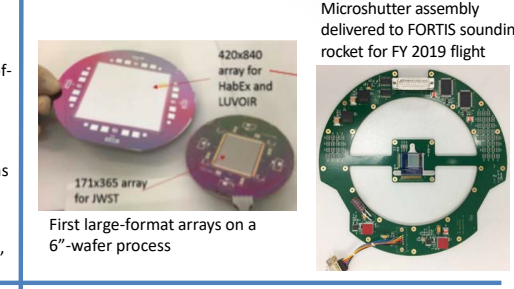
Current Funded Period of Performance:

Jan 2018 – Dec 2020

• TRL_{in} = 4 TRL_{Current} = 4 TRL_{Target} = 6

Scalable Microshutter Systems for UV, Visible, and Infrared Spectroscopy

PI: Matt Greenhouse, NASA GSFC



Objectives and Key Challenges:

- Eliminate macro-mechanisms required by the prior JWST magnetic actuation technology
- Develop large-area format and modular packaging for large-field-of-view applications
- Enable electrostatic actuation with high pixel operability
- Enable large-array format compatible with vibration/acoustic flight environment
- Enable 3-side-buttable packaging for large-field-of-view applications

Significance of Work:

- This technology uniquely enables the multi-object spectroscopy objectives of three Decadal Survey mission concept studies (HabEx, LUVOR, and CETUS)

Approach:

- Evolve shutter mechanical and electrical design to above objectives
- Incorporate improved oxide (ALD) to enable electrostatic actuation
- Incorporate 3D printing to increase manufacturability of large-format design
- Develop drive electronics for electrostatic actuation
- Develop 6"-wafer process and tooling necessitated by new array format requirement
- Incorporate anti-stiction techniques to improve pixel operability

Key Collaborators:

- Stephan McCandless (JHU)

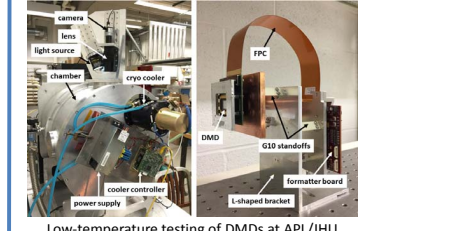
Development Period:

Oct 2018 – Sep 2021

• TRL_{in} = 3 TRL_{Current} = 3 TRL_{Target} = 5

Development of DMD Arrays for Use in Future Space Missions

PI: Zoran Ninkov / Rochester Institute of Technology



Objectives and Key Challenges:

- A technology is needed that allows target selection in a field of view that can be input to an imaging spectrometer for remote sensing and astronomy
- We are looking to modify and develop Digital Micro-mirror Devices (DMDs) for this application

Significance of Work:

- Existing DMDs need to have the commercial windows replaced with appropriate windows for the scientific application desired
- The devices need to be evaluated for survivability in a space environment

Approach:

- Use available 0.7 XGA DMDs to develop window removal procedures, and then replace delivered window with a hermetically sealed UV-transmissive window of Magnesium Fluoride, HEM sapphire, and fused silica
- Test and evaluate such devices and as well as Cinema DMDs

Key Collaborators:

- Sally Heep, Manuel Quijada, Jonny Pellish, and Tim Schwartz (NASA/GSFC)
- Massimo Robbeto (STScI)
- Alan Raisanen (RTI)

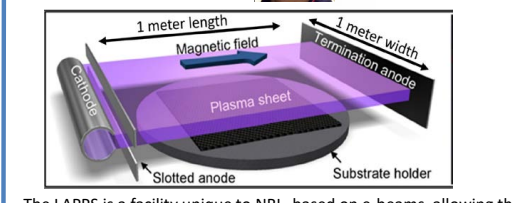
Current Funded Period of Performance:

May 2014 – May 2018

• TRL_{in} = 4 TRL_{Current} = 4 TRL_{Target} = 5

E-Beam-Generated Plasma to Enhance Performance of Protected Aluminum Mirrors for Large-Space-Telescope Astronomy

PI: Manuel Quijada/Code 551



Objectives and Key Challenges:

- Development of aluminum-based mirror coatings with high reflectance over a broad spectral range and particularly in the far-ultraviolet (FUV) spectral range
- Development of a plasma-based cleaning process to restore reflectance of mirror coatings in the FUV spectral region

Significance of Work:

- Successful oxide removal and passivation of Al-based coating will open the possibility of developing a large-scale process to enable the intrinsic high reflectance of Al-based reflectors on 1-m class mirrors

Approach:

- Produce samples of bare aluminum and overcoat with a metal-fluoride in the 2-m GSFC coating chamber
- Process various Al and metal-fluoride coatings by using the Large Area Plasma Processing System (LAPPs) at the Naval Research Laboratory (NRL)
- Demonstrate oxide removal and fluorination processing on the LAPPs meter-scale facility

Key Collaborators:

- Javier del Hoyo, Ed Wollack, and Vivek Dwivedi (NASA/GSFC)
- David Boris and Scott Walton (NRL)

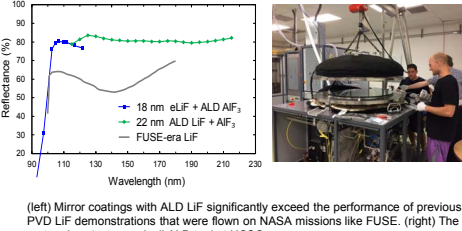
Current Funded Period of Performance:

Oct 2018 – Sep 2019

• TRL_{in} = 3 TRL_{Current} = 3 TRL_{Target} = 4

High Performance, Stable, and Scalable UV Aluminum Mirror Coatings using ALD

PI: John Hennessy / JPL



Objectives and Key Challenges:

- Atomic layer deposition (ALD) for wide bandpass (100–2500 nm) mirror coatings with emphasis on high performance in the FUV through the use of lithium fluoride based coatings
- Studying and enhancing long term performance stability
- Demonstrating ALD scalability trends towards large (>1 m) size mirrors
- Study fundamentals of aluminum deposition with respect to form birefringence, microstructure, and ALD compatibility
- Measurement and modeling of reflectance uniformity, wavefront error, and polarization retardance over the full aperture of shaped optics in the wavelength bands of interest to exoplanet coronagraphs

Significance of Work:

- An alternative to conventional physical vapor deposition (PVD) methods
- Improvements in performance, repeatability, and scalability are an enabling technology for LUVOR.

Approach:

- JPL's hydrogen fluoride based approach for ALD metal fluorides, as well as thermal atomic layer deposition (ALD) to maximize performance of UV protected-aluminum mirror coatings
- Exploiting the unique capabilities of ALD including nonlaminate structures and mixed composition fluoride overcoats
- Hardware at USCS originally developed for ALD-protected silver mirror coatings to demonstrate scale at ~1 meter diameter
- Facilities developed for flight projects at CU Boulder will allow detailed characterization of "flight-like" optics

Key Collaborators:

- April Jewell, K. Balasubramanian, Shouleh Nikzad (JPL)
- Kevin France, Brian Fleming (CU Boulder)
- Nobuhiko Kobayashi (USCS)


Current Funded Period of Performance:

Jan. 2020 – Dec. 2022

• TRL_{in} = 3 TRL_{Current} = 3 TRL_{Target} = 5

Ultraviolet Coatings, Materials, and Processes for Advanced Telescope Optics

PI: K. 'Baia' Balasubramanian / JPL



Objectives and Key Challenges:

- Development of UV coatings with high reflectivity (>90-95%), high uniformity (<1-0.1%), and wide bandpasses (~100 nm to 300-1000 nm) is a major technical challenge; this project aims to address this key challenge and develop feasible technical solutions
- Materials and process technology are the main challenges; improvements in existing technology base and significant innovations in coating technology such as Atomic Layer Deposition (ALD) are to be developed

Significance of Work:

- This is a key requirement for future Cosmic Origins and ExoPlanet missions, such as LUVOR and HabEx.

Approach:

- Develop a set of experimental data with MgF₂, AlF₃, and LiF-protected Al mirrors in the wavelength range 100-1000 nm for a comprehensive base of measurements, enabling full-scale developments with chosen materials and processes
- Investigate and develop enhanced coating processes including ALD
- Improve characterization and measurement techniques

Key Collaborators:

- John Hennessy, Shouleh Nikzad, Nasrat Raouf, Stuart Shaklan (JPL)
- Paul Scowen (ASU)
- Manuel Quijada (GSFC)

Current Funded Period of Performance:

Jan 2013 – Dec 2015

• TRL_{in} = 2-3 TRL_{As-Needed} = 3-4 TRL_{Target} = 5

LUVOIR UV/Optical Technologies

Based on Table 11-3 of LUVOIR Report

Black font = current status as of 2018, from Table 11-3 of LUVOIR Final Report

Orange font = SAT Quad Charts

7	System prototype demonstration in an operational environment.	SPRITE Prime Mission			FORTIS Rocket for 128x64 format							
LUVOIR Preliminary Design Review												
6	System / sub-system model or prototype demonstration in an operational environment.	SPRITE I&T					meets requirements for 100-150 nm					
5	Component and/or breadboard validation in relevant environment.	ALD on >20 cm optics; aging tests <u>Hennessy SAT; Quad</u>		Meets performance requirements, but is environmentally unstable	2021 Greenhouse SAT Goal	UV performance measurements on re-windowed XGAs <u>Ninkov SAT ; Quad</u>		Vallerga SAT			Figer SAT	8K x 8K devices exist with 18 micron pixels, lacks high speed subarray readout for guiding
4	Component and/or breadboard validation in lab environment					>5000:1 contrast achieved on re-windowed XGA format (1024x768) <u>Ninkov SAT ; Quad</u>		meets requirements for 100-150 nm; requires devel for large tile size and integration with cross-strip readout. GaN has better Solar-blind performance	Demonstrated 50% improved QE with CsI photocathode	4K x 4K devices exist, require development for 8K x 8K and readout optimization		
3	Analytical and experimental critical function and/or characteristic proof of concept	Meets performance requirements, but requires demonstration on meter-class optics, validation of uniformity, repeatability, and env. stability <u>PVD; Quijada SAT; Quad</u>				840x420 prototype demonstrated, but requires devel. to survive launch <u>Greenhouse SAT ; Quad</u>						
		> 50% over 100-115 nm, > 80% over 115-200 nm > 88% over 200 - 850 nm, > 96% over > 850 nm, < 1% reflectance non-uniformity over primary mirror in coronagraph bandpass (200-2000 nm)			840x420 format, two-side buttable, high contrast		200 mm x 200 mm tile size > 30% QE between 100-200 nm				8K x 9K format, < 7 μm pixels, three-side buttable, ~1 e- read noise, 10 ⁻⁴ e-/pix/s dark at 170K	
		Al+eLiF+MgF ₂ <u>Baseline</u>	Al+eLiF+AlF ₃	Al+eLiF	Microshutters <u>Baseline</u>	Micromirrors	CsI <u>Baseline</u>	GaN <u>Baseline</u>	Bi-alkali	Funnel micro	8K x 8K CMOS <u>Baseline</u>	4K x 4K CCDs
		Far-UV Broadband Coatings LUVOIR pg. 11-25			Configurable Shutters LUVOIR pg. 11-26		UV Microchannel Plate LUVOIR pg. 11-26				Visible Detectors LUVOIR pg. 11-27	

LUVOIR UV/Optical Technologies

Based on Table 11-3 of LUVOIR Report

Black font = current status as of 2018, from Table 11-3 of LUVOIR Final Report

Orange font = SAT Quad Charts

7	System prototype demonstration in an operational environment.	SPRITE Prime Mission			FORTIS Rocket for 128x64 format								
LUVOIR Preliminary Design Review													
6	System / sub-system model or prototype demonstration in an operational environment.	SPRITE I&T	WHAT			meets requirements for 100-150 nm	HAPPENS HERE?						
5	Component and/or breadboard validation in relevant environment.	ALD on >20 cm optics; aging tests <u>Hennessy SAT; Quad</u>		Meets performance requirements, but is environmentally unstable	2021 Greenhouse SAT Goal	UV performance measurements on re-windowed XGAs <u>Ninkov SAT ; Quad</u>	Vallerga SAT				Figer SAT	8K x 8K devices exist with 18 micron pixels, lacks high speed subarray readout for guiding	
4	Component and/or breadboard validation in lab environment					>5000:1 contrast achieved on re-windowed XGA format (1024x768) <u>Ninkov SAT ; Quad</u>	meets requirements for 100-150 nm; requires devel for large tile size and integration with cross-strip readout. GaN has better Solar-blind performance	Demonstrated 50% improved QE with CsI photocathode	4K x 4K devices exist, require development for 8K x 8K and readout optimization				
3	Analytical and experimental critical function and/or characteristic proof of concept	Meets performance requirements, but requires demonstration on meter-class optics, validation of uniformity, repeatability, and env. stability <u>PVD; Quijada SAT; Quad</u>			840x420 prototype demonstrated, but requires devel. to survive launch <u>Greenhouse SAT ; Quad</u>								
		> 50% over 100-115 nm, > 80% over 115-200 nm > 88% over 200 - 850 nm, > 96% over > 850 nm, < 1% reflectance non-uniformity over primary mirror in coronagraph bandpass (200-2000 nm)			840x420 format, two-side buttable, high contrast		200 mm x 200 mm tile size > 30% QE between 100-200 nm				8K x 9K format, < 7 μm pixels, three-side buttable, ~1 e- read noise, 10 ⁻⁴ e-/pix/s dark at 170K		
		Al+eLiF+MgF ₂ <u>Baseline</u>	Al+eLiF+AlF ₃	Al+eLiF	Microshutters <u>Baseline</u>	Micromirrors	CsI <u>Baseline</u>	GaN <u>Baseline</u>	Bi-alkali	Funnel micro	8K x 8K CMOS <u>Baseline</u>	4K x 4K CCDs	
		Far-UV Broadband Coatings LUVOIR pg. 11-25			Configurable Shutters LUVOIR pg. 11-26		UV Microchannel Plate LUVOIR pg. 11-26				Visible Detectors LUVOIR pg. 11-27		

LUVOIR Coronagraph Technologies

7	System prototype demonstration in an operational environment.													
6	System / sub-system model or prototype demonstration in an operational environment.								< 0.36 mas RMS line-of-sight residual error; <30 pm RMS focus, Mv = 5 source (WFIRST CGI Testbed)					
5	Component and/or breadboard validation in relevant environment.								<1e-8 contrast demonstrated with 48x48 actuator Xinetics DMs (WFIRST CGI Testbed)					H4RG-10 currently meets needed capability @ 170K
4	Component and/or breadboard validation in lab environment	6.3e-6 over 6% bandpass in air. Validated models w/ WFIRST CGI SPC demonstrations Soummer SAT							Available up to 64x64 actuators; 8.5e-9 contrast demonstrated with 32x32 actuators Bierden SAT				1k x 1k WFIRST detector: 7e-5 e-/pix/s dark current, 0 e- read noise, 2.3e-3 CIC	1.5e-3 e-/pix/s dark current, < 1e- read noise, 320 x 256 array size, Requires < 100 K temperatures
3	Analytical and experimental critical function and/or characteristic proof of concept		8.5e-9 contrast over 10% bandpass w/ unobscured pupil. SCDA modeling for unobscured, segmented pupil. Serabyn SAT	SCDA modeling results for unobscured, segmented pupil.	3.6e-10 contrast over 10% bandpass in DST. SCDA modeling for unobscured segmented pupil.				Model predicting <10 pm residual error w/ nonlinear ZWFS, Mv = 5 source	Concept study for guide star spacecraft and WFS control loop completed			Prototype devices fabricated with gains > 10x (>20x in at least one device)	
Options:	APLC Baseline	VC Baseline	PIAA	HLC	MEMS Baseline	PMN	Out-of-band Baseline	Low Order Baseline	Artificial GS	EMCCD Baseline	HMCCD	HgCdTe Photodiode Baseline	HgCdTe Avalanche	
Coronagraph Architecture					Deformable Mirrors		Wavefront Sensing			UV/Vis Detectors		NIR Detector		

and so on. . .

Ultrastable Telescope Technologies

Area	Active Sensing & Control				Low Disturbance			Structures			Mirrors and Mirror Mounting					
Technology	Segment Dynamic Sensing & Control	Laser Metrology	System Control Methodology	Thermal Sensing & Control	LOS Stability	Payload Isolation	Low Disturbance Mechanisms	Stable Composite Structures	Microdynamics	Stable Joining (Hinges/Latches)	Stable Mirrors	Mirror Mounting	PMSA Figure Actuation (if needed)	Coronagraph Design (LOWFS/HOWFS)	Infrastructure/ External Metrology	Path Forward for TRL Advancement
Current TRL	3	5	2	4	3	5	2	5	2	4	5	4	3	4/5	-	
Knowledge Gap	X		X	X	X		X		X	X		X	(X)			Analysis/ Measurements
Low-TRL Gap	X		X		X								(X)			Component-Level Demo
Mid-TRL Gap				X						X		X				Analysis/ Subsystem Demo
Engineering Gap		X				X		X			X				X	Analysis
System-Level Gap		X				X			X			X				System/ Subsystem Demos
Showstopper																Unknown

A proposal

- 1) Continue today's TIG activity on a regular basis with ~monthly meetings that drill down into particular topics. Format and schedule TBD.
- 2) Crowdsourcing the tech development tracking charts above to analyze the current state of the art, set expectations for progress, and identify new opportunities. Focus on the TRL5-6 gaps and the system vs. component issue.
- 3) Hopefully, extend this to tech development needed for other flagships in the X-ray and IR, involving the other PAGs where appropriate.

Comments?